

# **Reconfigurable Nanowire Electronics – Device Principles and Prospects**

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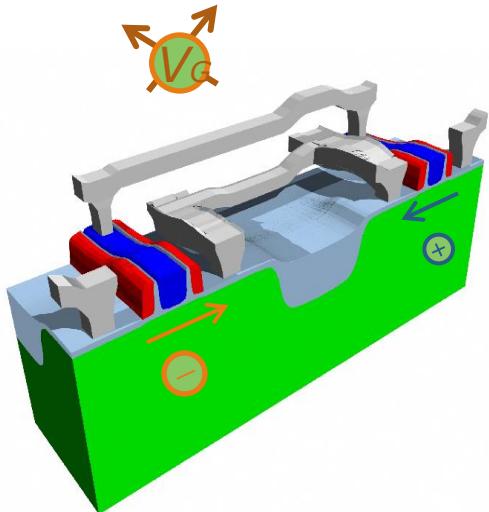
Namlab gGmbH Dresden Germany

March 25. 2013

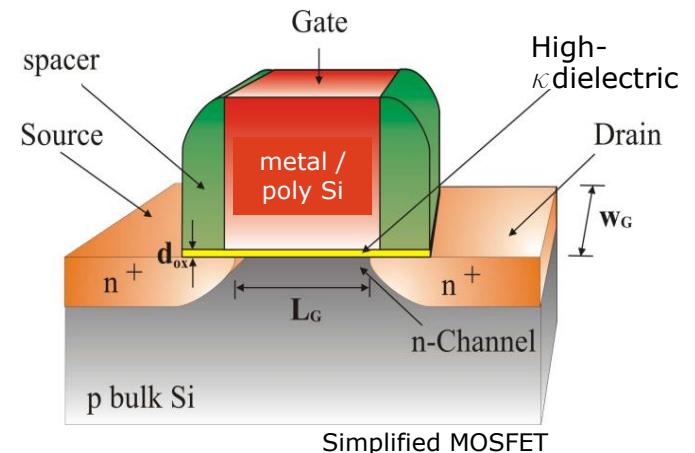
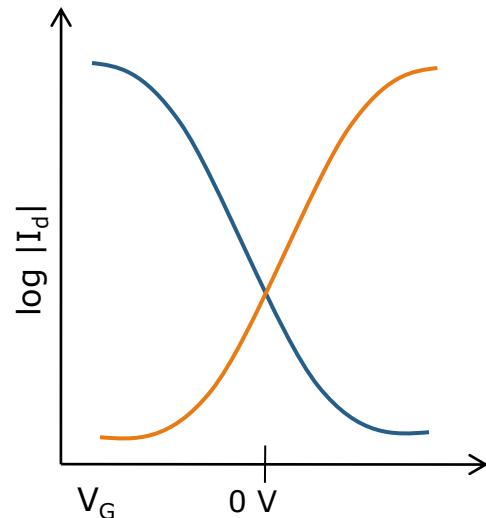
FED '13 – Workshop, Lausanne

# Basics and limitations of present CMOS technology

- ~ 88 % of IC market (\$320 bn: 2013) covered by **CMOS**
- **n-** / **p-** FETs alternated to constrain energy consumption to the switching event
- **n-** and **p-** FETs differ in technology (doping, dev. dimensions, strain, gate)
- Limited to static and single switch - function



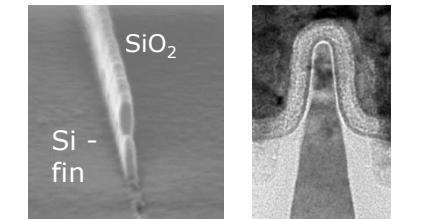
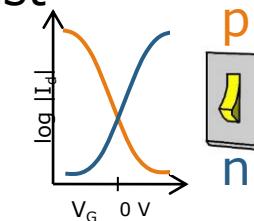
Inverter, modified from  
S. Selberherr TU Wien



# The quest for the “universal” transistor

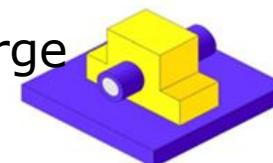
Wish list for a universal nano-device for logic operations:

- Provide both n- and p- FET characteristics upon request
  - > Electrically configurable characteristics
  - > No pre-program routine
- Cost-effective and reliable fabrication
  - > Compatible with silicon technology
  - > Suppression of doping variability
- Sufficiently high performance
  - > Enhanced electrostatics: multi-gated nanowire geometry
  - > Circuit maturity: drive next stage's charge

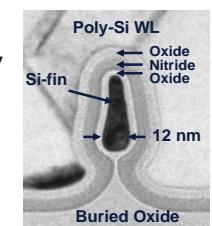


Infineon  
FinFET

Intel FinFET

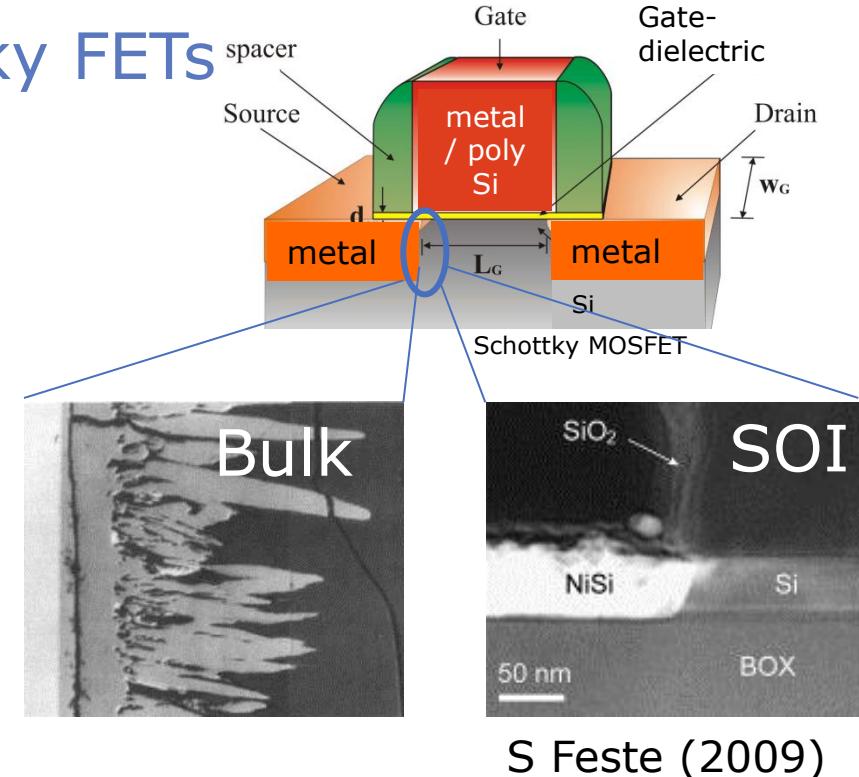


Infineon Trigate  
multibit flash



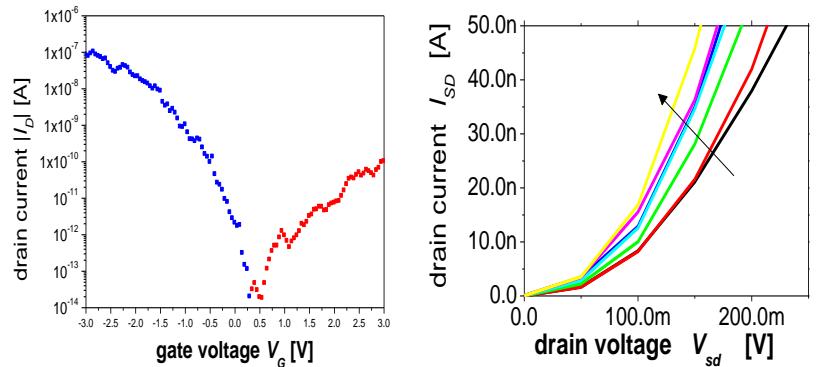
# Approach & challenges with Schottky FETs

- Intrinsic Si with near midgap metal electrodes.
- Filter out segments of ambipolar IV charact.



## Issues with SBFETs to be solved :

- High variability (varying junction areas)
- Low drive currents (tunnel barrier in on-state)
- Degraded off – state > *ambipolarity removed*
- Exponential turn-on in output characteristics  
(presence of energy barriers)



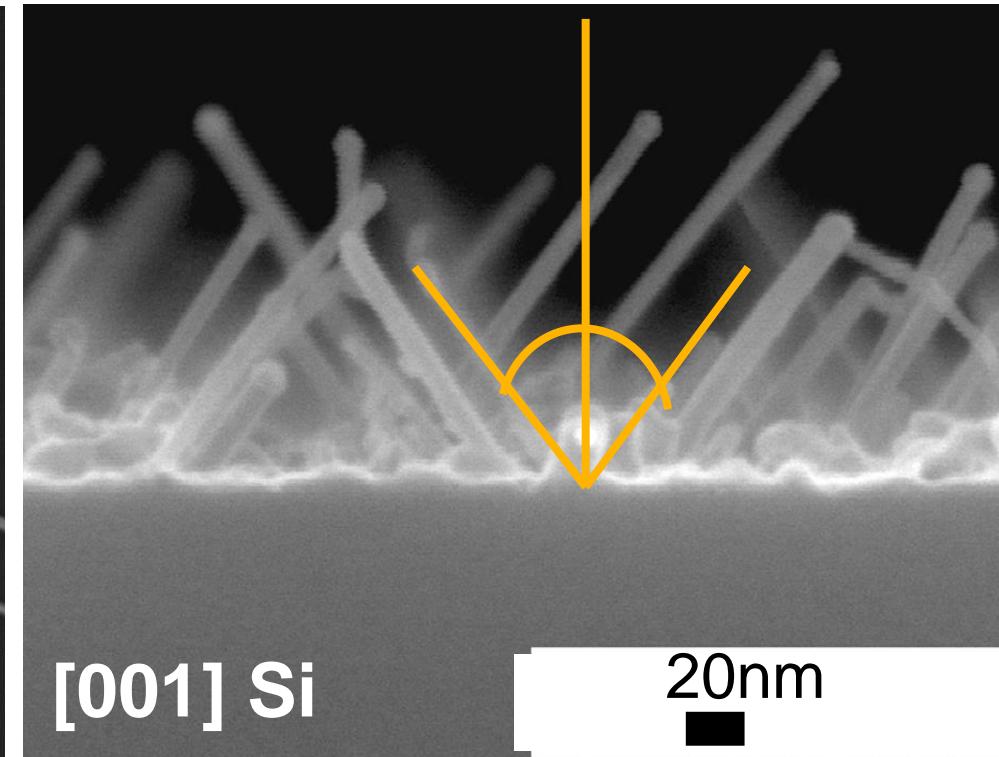
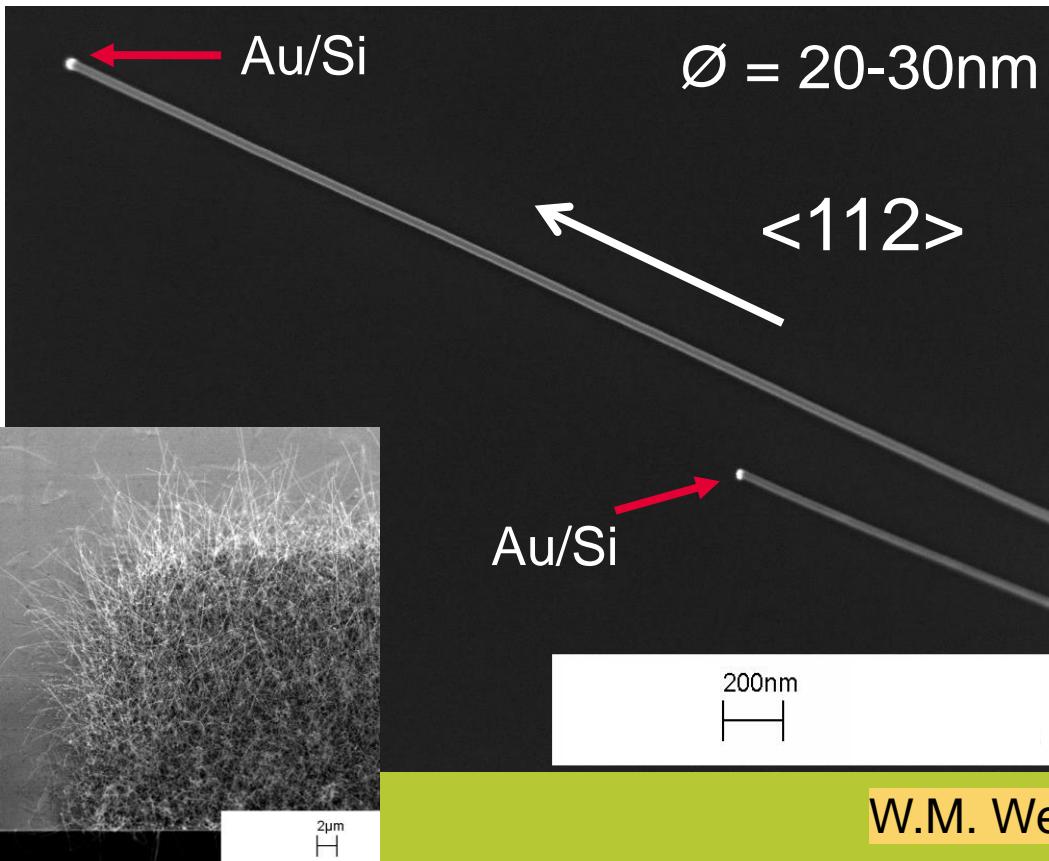
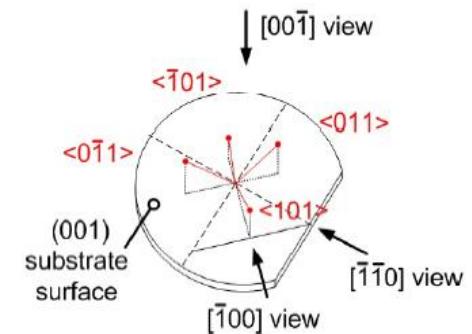
# Intrinsic Si-nanowires as vehicles

VLS / VSS growth

Controllable diameters, starting from  $\varnothing \sim 3\text{nm}$

Diameter dependent lattice direction

thinner NWs  $<- <110>; <112>; <111>$  -> thicker NWs

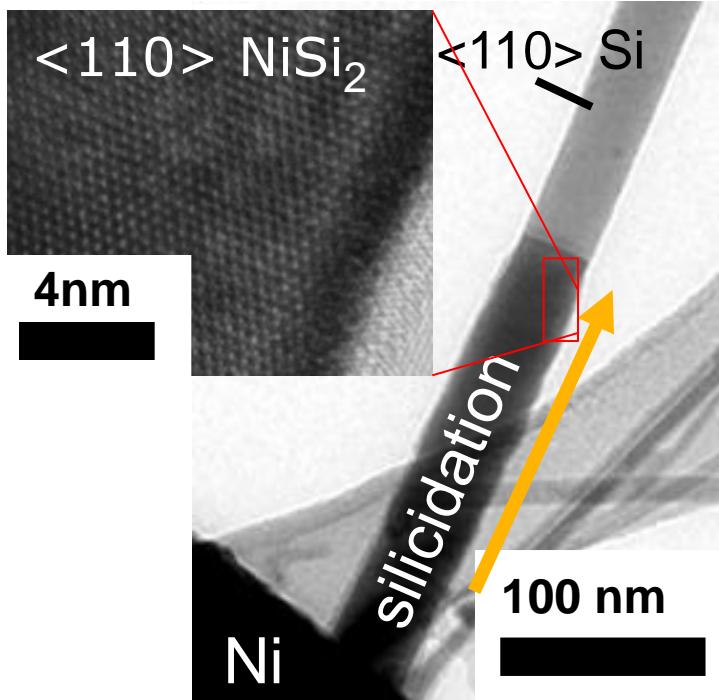


# Ni - Si nanowire solid state reaction kinetics

- Phase formation dependent on crystal orientation:

<110> -> Direct cubic  $\text{NiSi}_2$  lattice matched nucleation  
- 0.4 % lattice mismatch to Si <111>

<112> -> Sequence:  $\text{Ni}_2\text{Si}$  /  $\text{NiSi}$  /  $\text{NiSi}_2$



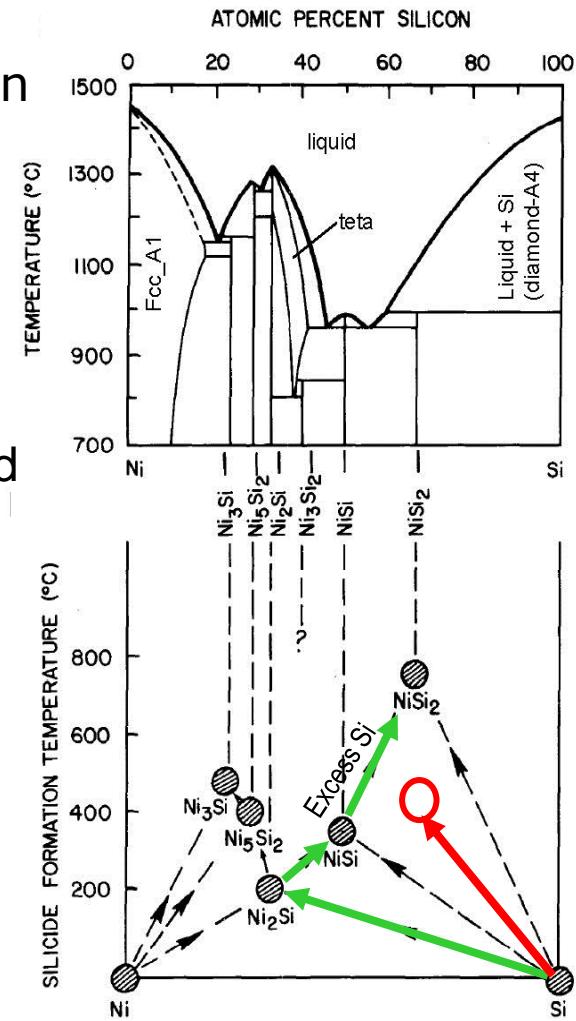
W.M. Weber et al. *Nano Lett.* **6**, 2660 (2006)

Long range, diffusion limited

$$d \sim \sqrt{t}$$

Short range, interface-reaction limited

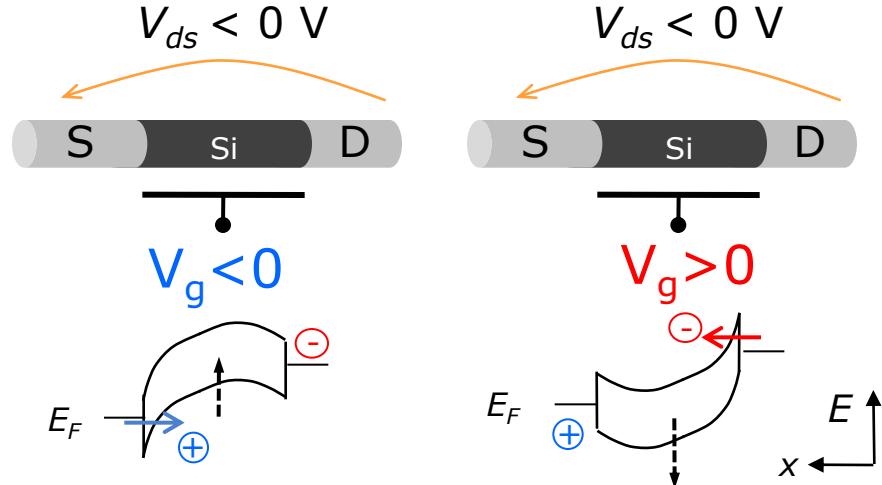
$$d \sim t$$



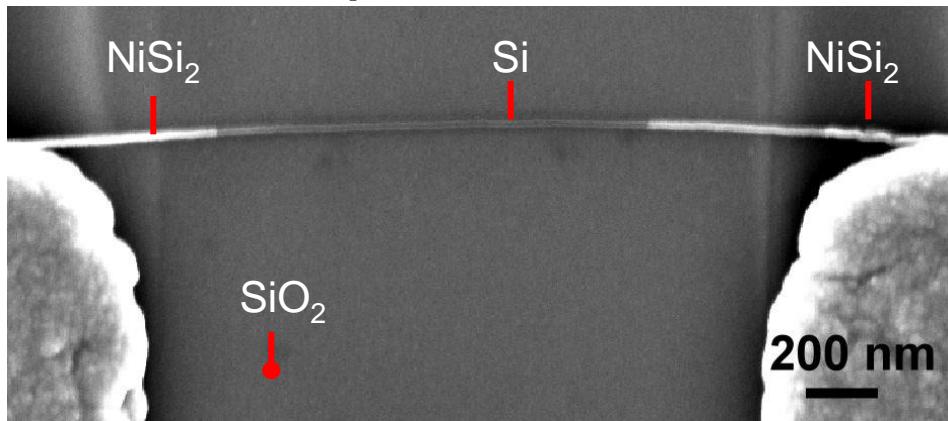
Sharp and flat interfaces-> known junction area -> low variability

# Working principle Schottky FETs

- i-Si: depletion / accumulation
- Field induced band bending at junctions
- Injection of both electrons and holes  
-> ambipolar behavior



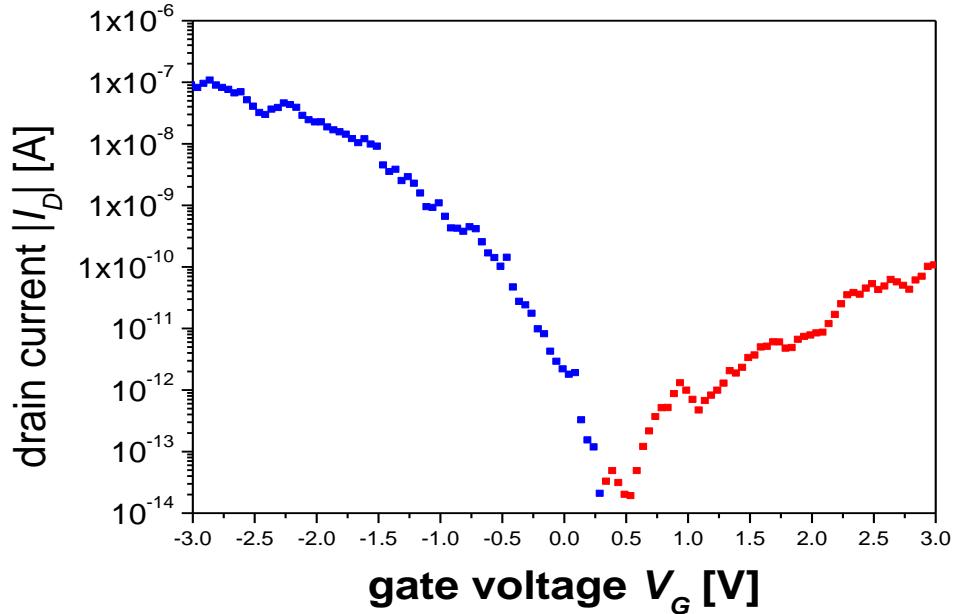
SEM top view of a Si-NW -FET



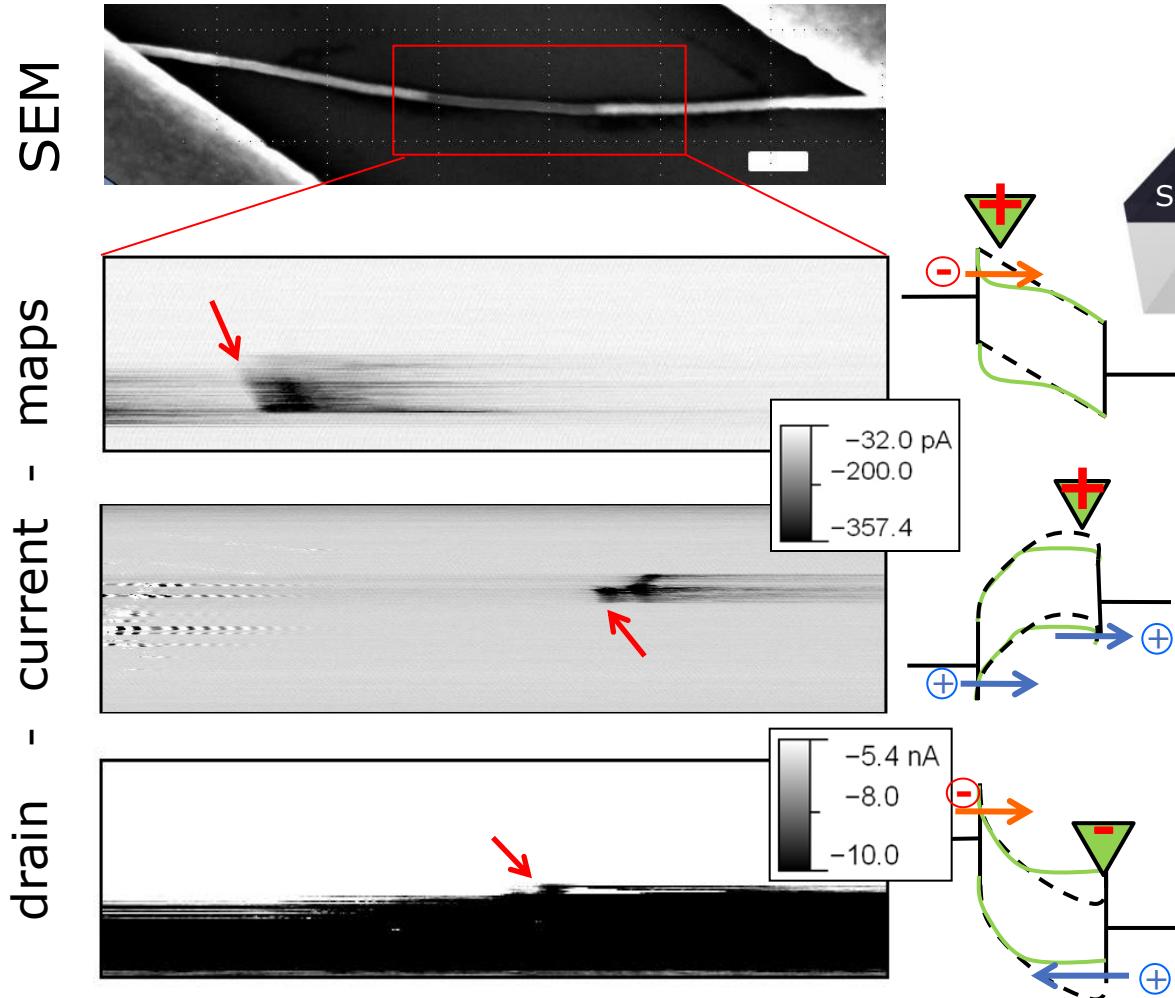
Reference: bulk  $\text{NiSi}_2/\text{Si}$

$$e\phi_B \text{ holes} = 0.39-0.48 \text{ eV}$$

$$e\phi_B \text{ electrons} = 0.66-0.75 \text{ eV}$$



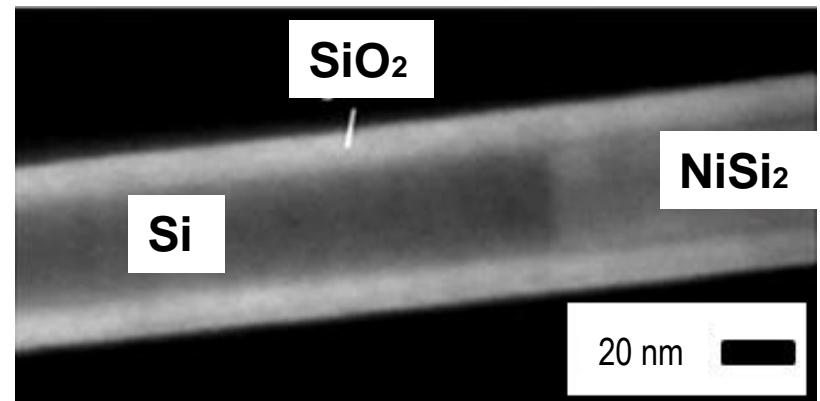
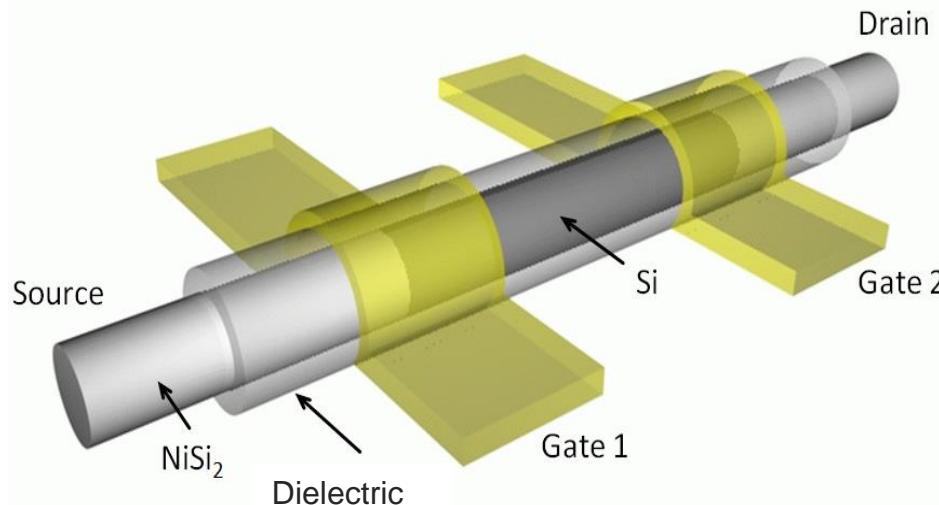
# Transport alteration in metal / Si / metal nanowires



- Turn device on with electron tunnel current
  - Enhance on-current by flushing holes at drain
  - Non-volatile program through charge trapping
- In contrast to a MOSFET a point potential selectively controls electron / hole transport

D. Martin, W. Weber et al. *Phys. Rev. Lett.* **107**, 216807 (2011)

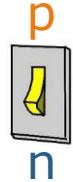
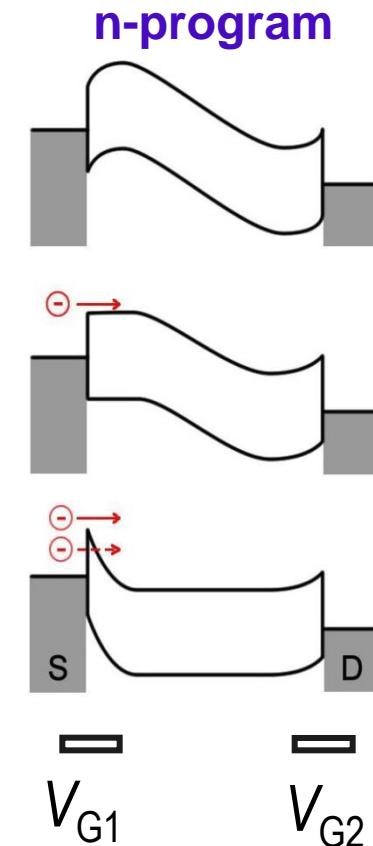
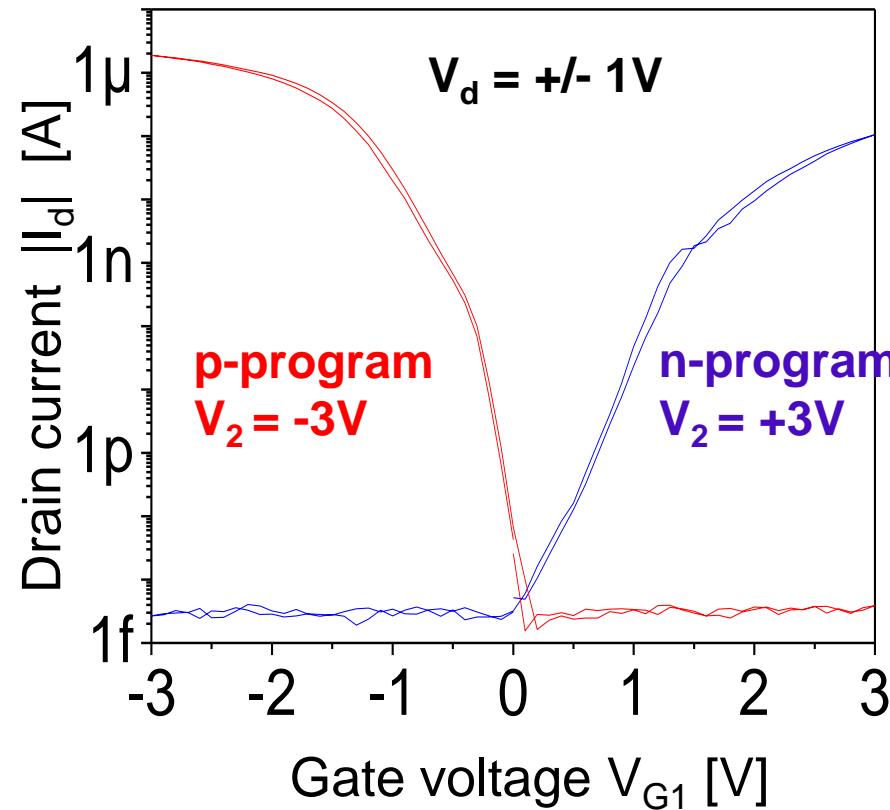
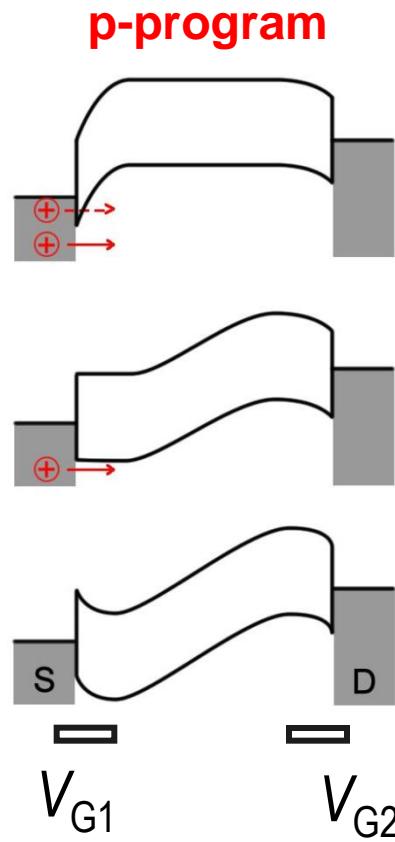
# RFET: Reconfigurable Si nanowire FET



- Longitudinal nanowire heterostructure: NiSi<sub>2</sub> / intrinsic Si / NiSi<sub>2</sub>
- Thermal silicon dioxide shell -> No need for extra spacer
- Individual gating of each Schottky junction -> valves for electrons / holes

A. Heinzig, W. Weber et. al *Nano Lett* 12, 119 (2012)  
Weber, W.M. et al. *IEEE Proc. Nanotech Conf.* 2008, p. 580 (2008)

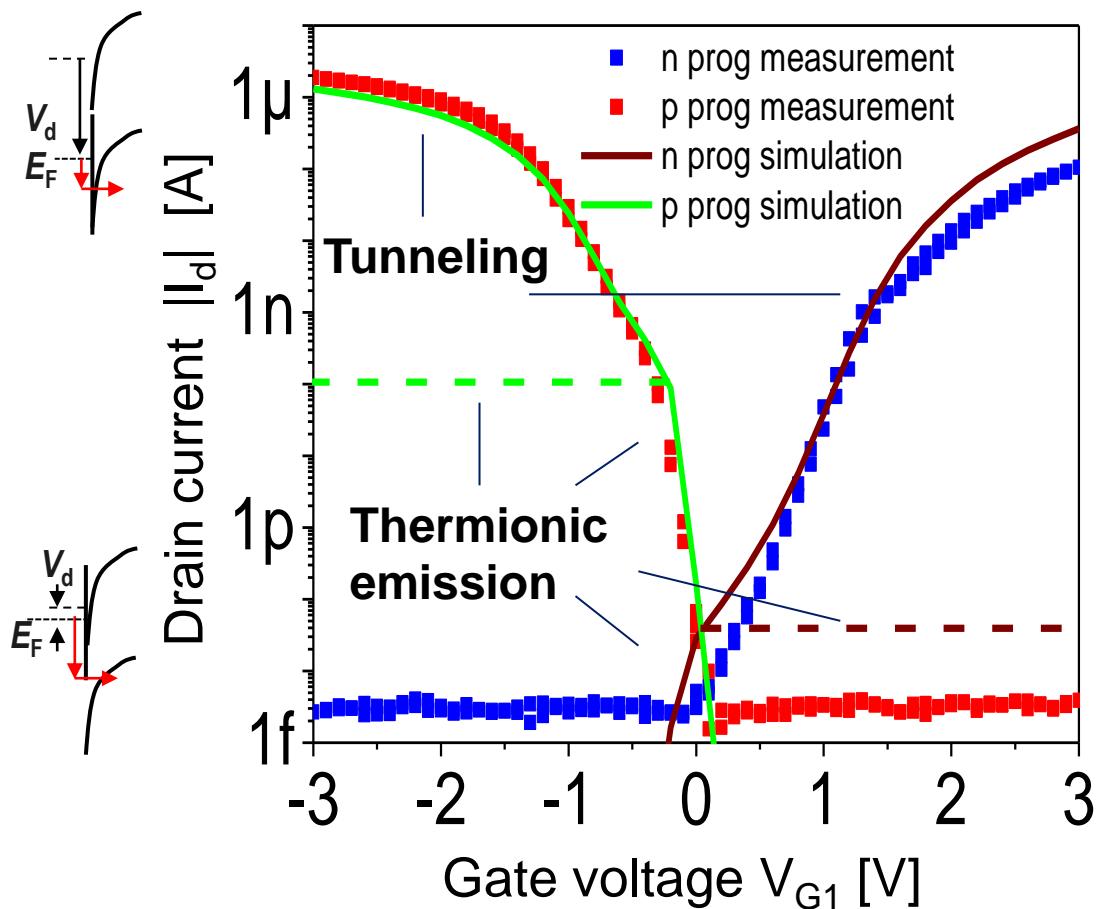
# Reconfigurable Si nanowire FETs



- Same FETs provide p- and n- type transport: leaner complexity
- Higher device functionality -> reprogrammable logic

$I_{on} / I_{off} > 5 \times 10^7$  ;  $J_{on} = 6 \times 10^5 \text{ A/cm}^2$  @  $V_d=1V$  ;  $g_m = 130 \mu\text{S}/\mu\text{m}$

# Reconfigurable Si nanowire FETs: transport



3D TCAD calc.(Sentaurus dev)

Drift diff. + WKB (tunneling)

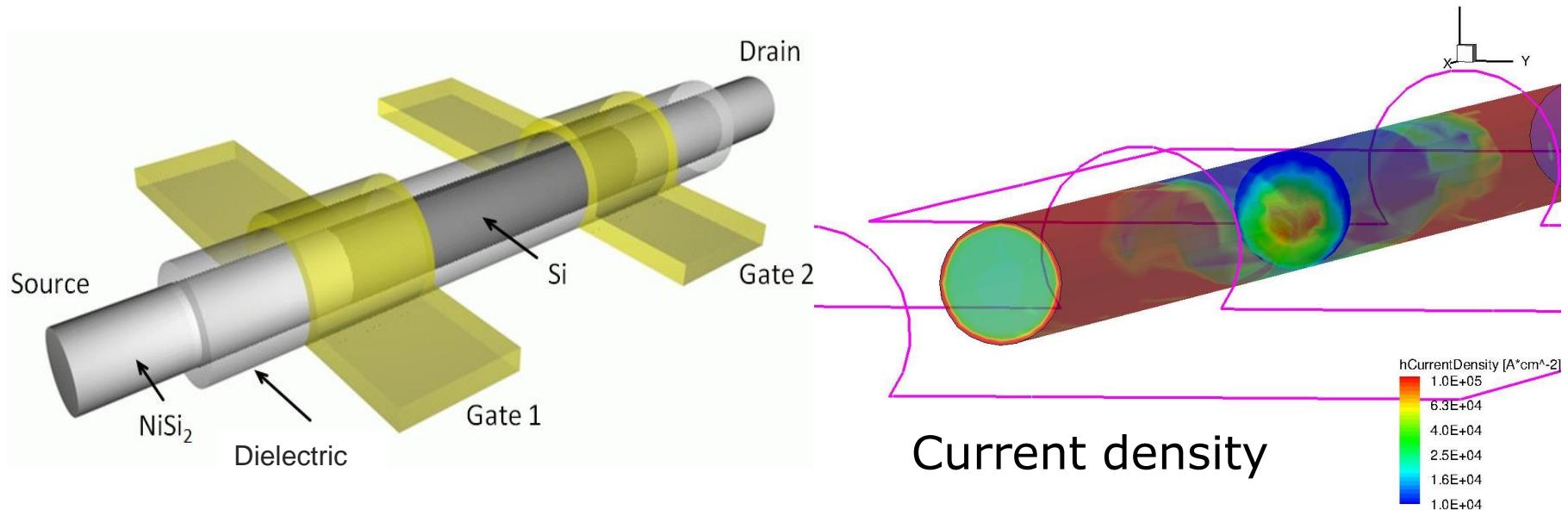
➤ Sub-  $V_{th}$  region divided into tunneling and thermionic emission

➤ Drive current dominated by tunneling

➤ N-FET degraded by unequal SBH

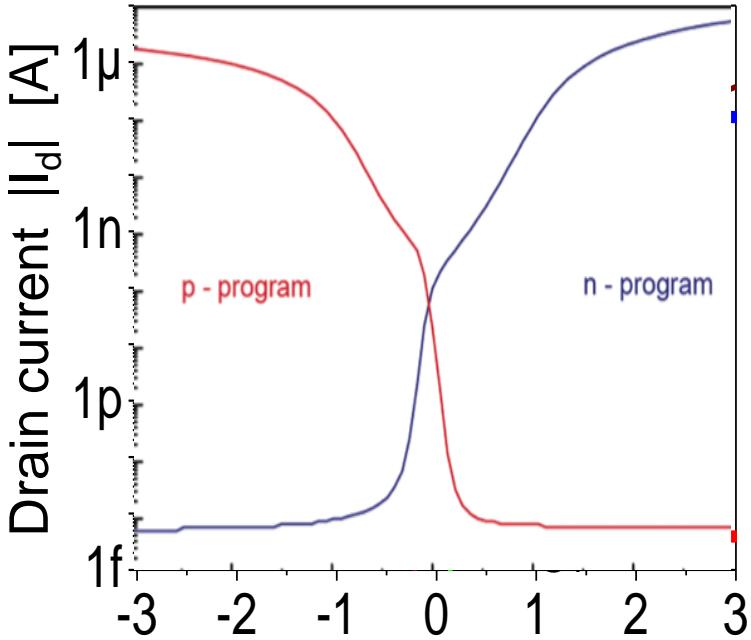
# Transport path: *sand glass form*

- Gated region at the nanowire surface / interface to dielectric
- Ungated region in the nanowire's core
- Less scattering expected in active region

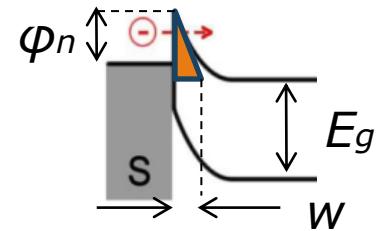


➤ Ultra low gate capacitances     $C = 3 \times 10^{-17} \text{ F}$  /    $C_g \sim 10^{-4} \text{ fF}/\mu\text{m}$

# Prospects for enhanced symmetry & performance

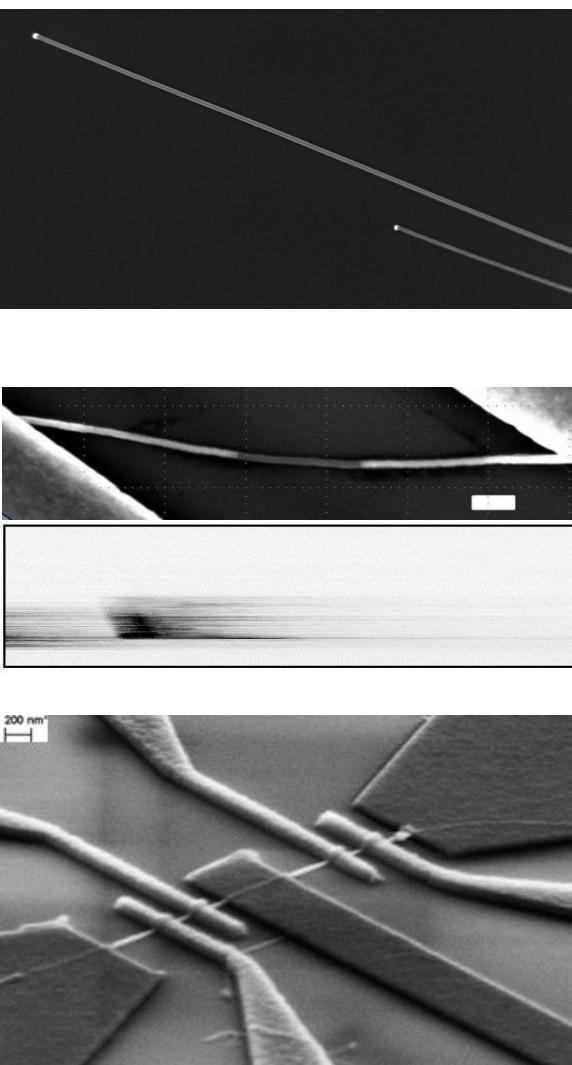


- Trivial adjustment of barrier height  $\varphi_n$  vs.  $\varphi_p$
  - Alter tunneling transmission
- $$T_{n,p}(\text{WKB}) \propto e^{\frac{-4w\sqrt{2m_{n,p}^*\phi_{n,p}}^{3/2}}{3q\hbar V}}$$
- Alter barrier width  $w$   
(electrost. geom,  $d_{si}$ ,  $d_{ox}$ ,  $\kappa$ )
  - Replace channel material  $m^*$ ,  $\varphi_{p,n}$ ,  $E_g$



- Ge with NiGe contacts, boost  $I_{on}$  without degrading  $I_{off}$

# Summary



## Formation of metal / silicon nanowire heterostructures

Formation of single crystal  $\text{NiSi}_2$

Sharp silicide to Si interface

## Transport properties

*carrier type* injected controlled by point potential

## Reconfigurable electronics

*p-* and *n-* type behavior on the same devices

No doping required

## Issues with SBFETs addressed:

- ✓ High variability (varying junction areas)
- ✓ Low drive currents (tunnel barrier in on-state)
- ✓ Degraded off – state > *ambipolarity removed*
- ✓ Exponential turn-on in output characteristics



Project ReproNano &  
Cluster of Excellence : cfAED



SAB: basic funding